



Inventor: Kie Y. Ahn et al.

Title: A Dielectric Layer Forming Method and Devices Formed Therewith

Assignee: Micron Technology, Inc.

Docket No. MI22-1534

#16/IDS  
MR  
4/11/03  
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APR - 7 2003  
TC 2800 MAIL ROOM

**INFORMATION DISCLOSURE STATEMENT**

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.  
Copies of documents listed on the Form PTO-1449 are enclosed.

No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 31 Mar 2003

Attorney: \_\_\_\_\_

James E. Lake  
Reg. No.: 44,854